AMENDMENTS TO THE CLAIMS

1. (Currently Amended) A method of simulating an area of interest (AOI) on a mask, the method comprising:

identifying the AOI;

generating an inspection image of the AOI;

providing design geometry information regarding an area outside the AOI without use of inspection images of that area; and

performing a simulation of the AOI based on the inspection image and the design geometry information.

- 2. (Original) The method of Claim 1, wherein providing design geometry information includes modifying data representing an area surrounding the AOI.
- 3. (Original) The method of Claim 2, wherein modifying data includes generating a virtual image of the area outside the AOI and combining the inspection image and the virtual image.
- 4. (Original) The method of Claim 3, wherein performing the simulation includes receiving the combined images.
- 5. (Original) The method of Claim 2, wherein modifying data includes generating a virtual image of the area outside the AOI and performing the simulation includes receiving the inspection image and the virtual image.
- 6. (Currently Amended) The method of Claim 5, wherein performing the wafer simulation further includes combining the inspection image and the virtual image.

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- 7. (Original) The method of Claim 1, wherein providing design geometry information includes accessing at least one of a GDS-II file, a MEBES file, and a bit map.
- 8. (Original) The method of Claim 1, wherein providing design geometry information includes extending geometries of a feature in the AOI.
- 9. (Original) The method of Claim 1, wherein providing design geometry information includes accessing information regarding another mask.
- 10. (Original) The method of Claim 9, wherein providing design geometry information includes accessing information regarding at least one of a trim mask and a phase shifting mask.
- 11. (Currently Amended) Data for a simulation engine, the data comprising:

first information from an inspection tool, the first information relating to a first area; and

second information from a design file, the second information relating to a second area outside the first area,

wherein the first information and the second information provide enhanced simulation accuracy for the first area.

- 12. (Original) The data of Claim 11, wherein the design file includes at least one of a GDS-II file, a MEBES file, and a bit map.
- 13. (Original) The data of Claim 11, wherein the second area is defined by at least one predetermined distance from a perimeter of the first area.

- 14. (Original) The data of Claim 11, wherein the second area is defined by a plurality of distances from a perimeter of the first area.
- 15. (Original) The data of Claim 11, wherein the first area is user defined.
- 16. (Original) The data of Claim 11, wherein the first and second areas are system defined.
- 17. (Original) The data of Claim 11, wherein the first area relates to a first mask and the second area relates to a second mask associated with the first mask.
- 18. (Original) A system for simulating a defect on a mask, the system comprising:

means for identifying an area of interest (AOI) including the defect;

means for providing an inspection image of the AOI;

means for providing design geometry information regarding an area surrounding the AOI; and

means for performing a simulation of the AOI based on the inspection image and the design geometry information.

- 19. (Original) The system of Claim 18, wherein the means for providing design geometry information includes means for modifying data representing an area surrounding the AOI.
- 20. (Original) The system of Claim 19, wherein the means for modifying data includes means for generating a virtual image

of the area surrounding the AOI and combining the inspection image and the virtual image.

- 21. (Original) The system of Claim 19, wherein the means for modifying data includes means for generating a virtual image of the area surrounding the AOI and the means for performing the simulation includes means for receiving the inspection image and the virtual image.
- 22. (Original) The system of Claim 18, wherein the means for providing design geometry information includes at least one of a GDS-II file, a MEBES file, and a bit map.
- 23. (Original) The system of Claim 18, wherein the means for providing design geometry information includes means for extending at least one geometry of a feature in the AOI to a predetermined distance.
- 24. (Original) The system of Claim 18, wherein the means for providing design geometry information includes means for accessing database information regarding another mask.
- 25. (Original) A simulated image of an area of interest on a wafer, the simulated image comprising:
- a feature, wherein the feature has an accuracy based on a mask inspection image having a defined area and design geometry information outside the defined area.
- 26. (Original) A method of improving simulation accuracy for an area of interest on a mask, the method comprising:

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generating a mask inspection image having a defined area, wherein simulating the mask inspection image provides a first accuracy; and

combining the mask inspection image with design geometry information outside the defined area to create a composite image, wherein simulating the composite image provides an improved accuracy compared to the first accuracy.

- 27. (Original) A computer program product for simulating an area of interest (AOI) on a mask, the computer program product comprising:
- a first set of instructions for receiving inspection information regarding the AOI;

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- a second set of instructions for receiving design geometry information regarding an area outside the AOI; and
- a third set of instructions for performing a simulation of the AOI based on the inspection information and the design geometry information.